



AF FFW

Docket No.: 9323.050.00-US
(PATENT)

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of:

In-Kwon Jeong

Confirmation No.: 1220

Application No.: 09/917,344

Group Art Unit: 1763

Filed: July 27, 2001

Examiner: Sylvia Macarthur

For: CMP SYSTEM AND METHOD FOR
EFFICIENTLY PROCESSING
SEMICONDUCTOR WAFERS

Customer No.: 30827

REQUEST FOR RECONSIDERATION

Mail Stop AF
Commissioner for Patents
Alexandria, VA 22313-1450

Dear Sir:

In response to the Final Office Action dated November 3, 2006, please consider the following remarks:

A Listing of the Claims begins on page **2** of this paper.

Remarks begin on page **20** of this paper.